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## Nanosecond and femtosecond excimer laser ablation of fused silica

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217	Direct Patterning of Quartz Substrates by Laser Ablation Using VUV Anti-Stokes Raman Pulses. <b>1992</b> , 285, 225		1
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215	Micropatterning of Quartz Substrates by Multi-Wavelength Vacuum-Ultraviolet Laser Ablation. <b>1993</b> , 32, 6185-6189		28
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211	X-ray photoelectron spectroscopy of uv laser irradiated sapphire and alumina. <b>1994</b> , 9, 2251-2257		20
210	Femtosecond excimer-laser-induced structure formation on polymers. <i>Applied Physics A: Solids and Surfaces</i> , <b>1994</b> , 59, 289-293		48
209	Novel ablation of fused quartz by preirradiation of vacuum-ultraviolet laser beams followed by fourth harmonics irradiation of Nd:YAG laser. <b>1994</b> , 65, 1510-1512		28
208	Ablation of polymer films by a femtosecond high-peak-power Ti:sapphire laser at 798 nm. <b>1994</b> , 65, 1850-1852	122	
207	Excimer laser ablation of Nd: YAG and Nd: glass. <b>1995</b> , 86, 223-227		16
206	Excimer laser ablation patterning of dielectric layers. <b>1995</b> , 86, 228-233		25
205	UV Optics and Coatings. <b>1995</b> , 123-171		0
204	An excimer laser-based micro analytical preparation technique for in-situ oxygen isotope analysis of silicate and oxide minerals. <b>1995</b> , 59, 4093-4101		57
203	Sub-picosecond UV laser ablation of metals. <b>1995</b> , 61, 33-37		352
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199	Three-dimensional optical storage inside transparent materials. <b>1996</b> , 21, 2023-5	744
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189	12. Laser Ablation in Optical Components and thin Films. <b>1997</b> , 573-624	3
188	Ultrafast-laser driven micro-explosions in transparent materials. <b>1997</b> , 71, 882-884	507
187	Optimization of the output beam homogeneity of short-pulse KrF amplifiers. <b>1997</b> , 36, 4094-8	1
186	Optimization of a beam delivery system for a short-pulse KrF laser used for material ablation. <b>1997</b> , 36, 7080-5	8
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182	Interaction of UV laser light with wide band gap materials: Mechanisms and effects. <b>1998</b> , 141, 709-718	15
181	Femtosecond laser microstructuring of materials. <b>1998</b> , 127-129, 875-880	68
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179	Direct fabrication of microgratings in fused quartz by laser-induced plasma-assisted ablation with a KrF excimer laser. <b>1998</b> , 23, 1486-8	86
178	Novel ablation of wide band-gap materials by multiwavelength excitation using a VUV-UV laser system. <b>1998</b> , 9, 99-103	4
177	Time-resolved surface scattering imaging of organic liquids under femtosecond KrF laser pulse excitation. <b>1998</b> , 73, 3498-3500	16
176	Ultrashort Laser Pulse Ablation of Hard Tissue*. <b>1998</b> , DLA2	
175	Pulsed Femtosecond Excimer Laser-Induced Chemically Clean Etching of Diamond. <b>1998</b> , 526, 123	3
174	Surface Modification and Ablation of Insulators Using a Tunable, Picosecond Mid-Infrared Laser. <b>1998</b> , 526, 3	2
173	Drilling of glass by excimer laser mask projection technique. <b>1999</b> ,	
172	FEMTOSECOND LASER-INDUCED DAMAGE OF DIELECTRICS. <b>1999</b> , 13, 1559-1578	39
171	Dopant induced ablation of poly(methyl methacrylate) at 308 nm. <b>1999</b> , 85, 1838-1847	51
170	Laser ablation and arc/spark solid sample introduction into inductively coupled plasma mass spectrometers. <b>1999</b> , 54, 381-409	194
169	Femtosecond laser-induced periodic structure writing on diamond crystals and microclusters. <b>1999</b> , 75, 3716-3718	144
168	High-precision in situ oxygen isotope analysis of quartz using an ArF laser. <b>1999</b> , 63, 687-702	25
167	Relief gratings on Er/Yb-doped borosilicate glasses and waveguides by excimer laser ablation. <b>2000</b> , 153, 200-210	12
166	XeCl laser ablation of Al <sub>2</sub> O <sub>3</sub> /TiC ceramics. <b>2000</b> , 154-155, 29-34	12
165	Photoablation with sub-10 fs laser pulses. <b>2000</b> , 154-155, 11-16	49

164	Various structural changes in SiO <sub>2</sub> introduced by one-photon excitation with undulator and two-photon excitation with excimer laser. <b>2000</b> , 168, 92-95	3
163	Photon absorption of conduction-band electrons and their effects on laser-induced damage to optical materials. <b>2000</b> , 61, 16522-16529	14
162	Drilling of glass by excimer laser mask projection technique. <b>2000</b> , 12, 189	22
161	Chapter 4 Laser ablation for inductively coupled plasma-mass spectrometry. <b>2000</b> , 34, 445-501	5
160	Periodic nanostructure array in crossed holographic gratings on silica glass by two interfered infrared-femtosecond laser pulses. <b>2001</b> , 79, 1228-1230	62
159	Hole drilling of silica glass with infrared femtosecond laser pulses.	
158	Three-dimensional hole drilling of silica glass from the rear surface with femtosecond laser pulses. <b>2001</b> , 26, 1912-4	199
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155	Creation of micro-holes on glass surface by femtosecond laser through the ejection of molten material. <b>2001</b> , 292, 202-209	15
154	Ultrafast laser micromachining with a liquid film. <b>2001</b> ,	
153	Fabrication of nonerasable gratings in SiO <sub>2</sub> glasses by a two-beam holographic method using infrared femtosecond laser pulses. <b>2001</b> ,	1
152	Energy deposition at front and rear surfaces during picosecond laser interaction with fused silica. <b>2001</b> , 78, 2840-2842	32
151	Velocity angular distribution of ground level atomic silicon in the plume of laser ablated silica. <b>2001</b> , 89, 1927	2
150	Inert gas beam delivery for ultrafast laser micromachining at ambient pressure. <b>2001</b> , 89, 8219-8224	38
149	Laser ablation construction of on-column reagent addition devices for capillary electrophoresis. <b>2002</b> , 74, 1572-7	13
148	Holographic writing of micro-gratings and nanostructures on amorphous SiO <sub>2</sub> by near infrared femtosecond pulses. <b>2002</b> , 191, 89-97	11
147	Encoding of holographic grating and periodic nano-structure by femtosecond laser pulse. <b>2002</b> , 197-198, 688-698	34

146	Fabrication of diffractive phase elements for the UV-range by laser ablation patterning of dielectric layers. <b>2002</b> , 197-198, 856-861	13
145	Microetching of fused silica by laser ablation of organic solution with XeCl excimer laser. <b>2002</b> , 186, 552-555	41
144	Femtosecond laser damage of a high reflecting mirror. <b>2002</b> , 408, 297-301	37
143	Fabrication of micro-optical elements in quartz by laser induced backside wet etching. <b>2003</b> , 67-68, 438-444	60
142	Preparation of nano-size particles of silver with femtosecond laser ablation in water. <b>2003</b> , 206, 314-320	184
141	Surface micro-fabrication of silica glass by excimer laser irradiation of organic solvent. <b>2003</b> , 158, 179-182	69
140	Reactive pulsed laser deposition of silica and doped silica thin films. <b>2003</b> , 437, 211-216	2
139	Processing of metals and semiconductors by a femtosecond laser-based microfabrication system. <b>2003</b> ,	19
138	Three-dimensional optical storage by use of an ultrafast laser. <b>2003</b> , 5069, 264	
137	Fabrication of diffractive optical elements by ArF-laser ablation of fused silica. <b>2003</b> , 4977, 235	6
136	Development of Dicing Technique for Thin Semiconductor Substrate by Using Temporally Shaped Femtosecond Laser. <i>IEEJ Transactions on Electronics, Information and Systems</i> , <b>2003</b> , 123, 1977-1981	0.1
135	Microfabrication of Transparent Materials by Laser Processing. <b>2003</b> , 339-357	
134	Excimer laser inscribed submicron period relief gratings in InOx films and overlaid waveguides. <b>2004</b> , 95, 1634-1641	10
133	Laser Application of Polymers. 51-246	118
132	Quartz micromachining using laser plasma soft x rays and ultraviolet laser light. <b>2004</b> , 85, 1274-1276	36
131	Photo-Excited Processes, Diagnostics and Applications. <b>2004</b> ,	3
130	Plasma effects in picosecond-femtosecond UV laser ablation of polymers. <b>2004</b> , 79, 869-873	21
129	Development of dicing technique for thin semiconductor substrate using temporally shaped femtosecond laser. <b>2004</b> , 149, 43-48	4

128	Micron- and submicron-sized surface patterning of silica glass by LIBWE method. <b>2004</b> , 166, 129-133	45
127	Femtosecond laser micro-structuring of aluminium under helium. <b>2004</b> , 230, 50-59	51
126	Adjustment of laser facet film reflectivity by ablation etching. <b>2004</b> , 16, 42-44	2
125	Laser drilling and routing in optical fibers and tapered micropipettes using excimer, femtosecond, and CO <sub>2</sub> lasers. <b>2004</b> ,	3
124	Ablation and compaction of amorphous SiO <sub>2</sub> irradiated with ArF excimer laser. <b>2004</b> , 337, 241-253	27
123	Micromachining of inorganic transparent materials using pulsed laser plasma soft x-rays at 10 nm (Invited Paper). <b>2005</b> , 5713, 9	
122	Influence of ambient medium on femtosecond laser processing of silicon. <b>2005</b> , 247, 163-168	48
121	Femtosecond laser micromachining of grooves in silicon with 800 nm pulses. <b>2005</b> , 80, 1717-1724	83
120	Time-Resolving Image Analysis of Drilling of Thin Silicon Substrates with Femtosecond Laser Ablation. <b>2005</b> , 44, 7998-8003	8
119	Periodic unmixing of a binary metallic vapor. <b>2005</b> , 72,	1
118	Excimer laser ablation of glass-based arrayed microstructures for biomedical, mechanical, and optical applications. <b>2005</b> , 17, 38-46	10
117	10,000-hour maintenance-free operation of 1-W femtosecond laser for industrial applications.	
116	Via Drilling. <b>2005</b> , 187-200	
115	Crack-free direct-writing on glass using a low-power UV laser in the manufacture of a microfluidic chip. <b>2005</b> , 15, 1147-1156	89
114	Laser ablation of toluene liquid for surface micro-structuring of silica glass. <b>2006</b> , 252, 4387-4391	31
113	Flat-top profile of an excimer-laser beam generated using beam-splitter gratings. <b>2006</b> , 268, 289-293	23
112	Laser induced formation of periodic nanostructures in silicon covered by SiO <sub>2</sub> . <b>2006</b> , 82, 679-682	8
111	Ultra-short laser processing of transparent material at the interface to liquid. <b>2006</b> , 39, 1398-1404	16

110	Optodynamic monitoring of the laser drilling of through-holes in glass ampoules. <b>2006</b> , 17, 2828-2834	10
109	Rapid cell-patterning and microfluidic chip fabrication by crack-free CO <sub>2</sub> laser ablation on glass. <b>2006</b> , 16, 1143-1153	39
108	Silica nanomachining using laser plasma soft x rays. <b>2006</b> , 89, 101118	19
107	The reduction of the threshold fluence at laser-induced backside wet etching due to a liquid-mediated photochemical mechanism. <b>2007</b> , 40, 3060-3064	8
106	Micro patterning of fused silica by ArF- and F <sub>2</sub> -laser ablation. <b>2007</b> , 59, 206-209	19
105	Ablation of inorganic materials using laser plasma soft X-rays. <b>2007</b> ,	
104	Direct Nanomachining of Inorganic Transparent Materials Using Laser Plasma Soft X-Rays. <b>2007</b> , 59, 279-284	2
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102	Fabrication of a microfluidic bioarray device using laser-machined surface microstructures. <b>2007</b> ,	3
101	Surface microstructuring of silica glass by laser-induced backside wet etching with a DPSS UV laser. <b>2007</b> , 253, 8287-8291	16
100	Ablation with femtosecond pulses: The effect of temporal contrast. <b>2007</b> , 253, 7779-7782	5
99	Indirect laser etching of fused silica: Towards high etching rate processing. <b>2007</b> , 253, 8091-8096	13
98	Ablation induced by single-and multiple-femtosecond laser pulses in lithium niobate. <b>2007</b> , 17, 1378-1381	16
97	Micro-machining of metals, ceramics and polymers using nanosecond lasers. <b>2007</b> , 33, 95-102	154
96	Micro patterning of fused silica by laser ablation mediated by solid coating absorption. <b>2008</b> , 93, 65-68	20
95	Micromachining of inorganic materials using plasma soft x-rays. <b>2008</b> , 91, 45-51	
94	Chemical and structural changes of quartz surfaces due to structuring by laser-induced backside wet etching. <b>2008</b> , 10, 3195-202	11
93	Laser-Induced Backside Wet Etching of Transparent Materials with Organic and Metallic Absorbers. <b>2008</b> , 2008, 1-13	25



92	Laser-induced backside dry etching: wavelength dependence. <b>2008</b> , 41, 175501	10
91	Sub-wavelength ripples in fused silica after irradiation of the solid/liquid interface with ultrashort laser pulses. <b>2008</b> , 19, 495301	7
90	190nm excimer laser drilling of glass slices: Dependence of drilling rate and via hole shape on the diameter of the via hole. <b>2009</b> , 27, L42	1
89	Breakdown limits of optical multimode fibers for the application of nanosecond laser pulses at 532 nm and 1064 nm wavelength. <b>2009</b> , 255, 5519-5522	6
88	Excimer laser-induced microbumps on preheated BK7-glass. <b>2009</b> , 95, 639-642	5
87	Fabrication of micro-gratings on Au thin film by femtosecond laser interference with different pulse durations. <b>2009</b> , 255, 8483-8487	11
86	Silica nano-ablation using laser plasma soft x-rays. <b>2009</b> ,	
85	????????X?????????????????. <b>2009</b> , 60, 687-692	
84	Deep trenches fabricated by laser-induced backside wet etching for guiding light. <b>2009</b> ,	
83	Flexible fabrication of deep microstructures by laser-induced backside wet etching. <b>2010</b> ,	2
82	Laser Ablation in Atomic Spectroscopy. <b>2010</b> ,	1
81	Laser Micromachining. <i>Springer Series in Materials Science</i> , <b>2010</b> , 169-187	0.9
80	Surface Modification Induced by Femtosecond Laser Pulses in Lithium Niobate. <b>2011</b> , 142, 134-137	
79	Diffraction shaping of excimer-laser beams for pulsed laser deposition. <b>2011</b> , 6,	5
78	Fabrication of Micropatterns on Silica Glass by a Room-Temperature Imprinting Method. <b>2011</b> , 94, 2319-2322	10
77	Ablation of silica glass induced by laser plasma soft X-ray irradiation. <b>2011</b> , 94, 30-35	
76	Femtosecond laser-induced mesoporous structures on silicon surface. <b>2011</b> , 284, 317-321	8
75	Laser processing of optical fibers: new photosensitivity findings, refractive index engineering and surface structuring. <b>2012</b> , 374-452	1

74	Low-temperature atmospheric pressure argon plasma treatment and hybrid laser-plasma ablation of barite crown and heavy flint glass. <b>2012</b> , 51, 3847-52		21
73	Laser-induced front side etching of fused silica with short and ultra-short laser pulses. <b>2012</b> ,		5
72	Laser-induced front side etching of fused silica with XeF excimer laser using thin metal layers. <b>2012</b> , 258, 9138-9142		16
71	Influence of mechanical stress on nanosecond laser-induced damage threshold of fused silica. <b>2012</b> , 258, 9153-9156		4
70	Laser-induced front side and back side etching of fused silica with KrF and XeF excimer lasers using metallic absorber layers: A comparison. <b>2012</b> , 258, 9742-9746		14
69	Ablation effects of femtosecond laser functionalization on steel surfaces. <b>2012</b> , 207, 102-109		33
68	Laser-Induced front Side Etching: An Easy and Fast Method for Sub- $\mu\text{m}$ Structuring of Dielectrics. <b>2012</b> , 39, 542-547		8
67	Laser-induced front side etching of fused silica with KrF excimer laser using thin chromium layers. <b>2012</b> , 209, 1114-1118		12
66	Laser surface patterning using a Michelson interferometer and femtosecond laser radiation. <i>Optics and Laser Technology</i> , <b>2012</b> , 44, 2072-2075	4.2	18
65	Beam diameter dependence of surface damage threshold of fused silica fibers and preforms for nanosecond laser treatment at 1064 nm wavelength. <b>2013</b> , 276, 312-316		7
64	Laser-induced fabrication of randomly distributed nanostructures in fused silica surfaces. <b>2013</b> , 111, 1025-1030		10
63	Micro Metal Forming. <i>Lecture Notes in Production Engineering</i> , <b>2013</b> ,	0	21
62	Laser-induced front side etching of CaF <sub>2</sub> crystals with KrF excimer laser. <b>2013</b> , 265, 648-652		7
61	Laser-induced front side etching of fused silica with femtosecond laser radiation using thin metal layers. <b>2013</b> , 278, 255-258		3
60	Femtosecond-laser ablation dynamics of dielectrics: basics and applications for thin films. <b>2013</b> , 76, 036502		242
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58	Nanosecond laser-induced back side wet etching of fused silica with a copper-based absorber liquid. <b>2014</b> ,		1
57	Plasmonic formation mechanism of periodic 100-nm-structures upon femtosecond laser irradiation of silicon in water. <b>2014</b> , 116, 074902		77

56	Structuring of glass fibre surfaces by laser-induced front side etching. <b>2014</b> , 302, 52-57	7
55	Electron dynamics triggered by double attosecond pulses: Simulations based on time-dependent density functional theory. <b>2014</b> , 378, 95-99	5
54	Micromachining And Patterning In Micro/Nano Scale On Macroscopic Areas. <b>2015</b> , 60, 2221-2234	5
53	Fast microstructuring of silica glasses surface by NIR laser radiation. <i>Optics and Lasers in Engineering</i> , <b>2015</b> , 68, 16-24	4.6 8
52	Dynamics of the laser-induced nanostructuring of thin metal layers: experiment and theory. <b>2015</b> , 2, 026501	6
51	Programmable Laser-Assisted Surface Microfabrication on a Poly(Vinyl Alcohol)-Coated Glass Chip with Self-Changing Cell Adhesivity for Heterotypic Cell Patterning. <b>2015</b> , 7, 22322-32	16
50	Nanosecond laser-induced nanostructuring of thin metal layers and dielectric surfaces. <b>2015</b> ,	0
49	Laser etching technique using bubble jet impact for glass substrates. <b>2015</b> , 118, 1501-1508	1
48	Tribological performance of laser peened TiB <sub>2</sub> Al <sub>2</sub> O <sub>3</sub> . <b>2015</b> , 322-323, 203-217	54
47	Ge-doped silica nanoparticles: production and characterisation. <b>2016</b> , 6, 2213	4
46	Space weathering of silicates simulated by successive laser irradiation: In situ reflectance measurements of Fo90, Fo99+, and SiO <sub>2</sub> . <b>2016</b> , 51, 261-275	13
45	The effect of surface microstructure on the optical reflectance of monocrystalline silicon. <b>2016</b> , 3, 125020	0
44	Nanosecond laser damage of optical multimode fibers. <b>2016</b> ,	
43	Non-conventional and Hybrid Methods of Bone Machining. <b>2016</b> , 45-98	
42	Influence of the confinement on laser-induced dry etching at the rear side of fused silica. <b>2016</b> , 122, 1	5
41	Periodic surface structure creation by UV femtosecond pulses on silicon. <b>2017</b> ,	
40	Laser Irradiation Responses of a Single-Crystal Diamond Produced by Different Crystal Growth Methods. <b>2017</b> , 7, 815	9
39	Effect of ablative laser on in vitro transungual delivery. <b>2018</b> , 544, 402-414	13

38	Lab-in-a-fiber sensors: A review. <b>2019</b> , 217, 111105		17
37	Study of silica-based intrinsically emitting nanoparticles produced by an excimer laser. <b>2019</b> , 10, 211-221		0
36	Surface characteristics of alkaline earth boro-aluminosilicate glass following single picosecond laser pulse exposure at different focal positions. <i>Optics and Laser Technology</i> , <b>2019</b> , 113, 437-446	4.2	3
35	Microchannel Fabrication in Fused Quartz by Backside Laser-Induced Plasma Ablation Using 248 nm KrF Excimer Laser. <b>2019</b> , 9, 5320		5
34	Drilling of sub-100 $\mu\text{m}$ hourglass-shaped holes in diamond with femtosecond laser pulses. <b>2020</b> , 50, 201-204		3
33	Laser-induced reactive microplasma for etching of fused silica. <b>2020</b> , 126, 1		6
32	Gas ejection mechanism of glass structuring induced by nanosecond laser pulses. <b>2020</b> , 126, 1		0
31	Deep ultraviolet excimer laser processing for the micro via hole on semiconductor package. <b>2020</b> , 32, 022076		3
30	Self-focusing of UV radiation in 1 mm scale plasma in a deep ablative crater produced by 100 ns, 1 GW KrF laser pulse in the context of ICF. <b>2020</b> , 5, 035401		4
29	Room-Temperature Laser Synthesis in Liquid of Oxide, Metal-Oxide Core-Shells, and Doped Oxide Nanoparticles. <b>2020</b> , 26, 9206-9242		94
28	Backward Flux Re-Deposition Patterns during Multi-Spot Laser Ablation of Stainless Steel with Picosecond and Femtosecond Pulses in Air. <b>2021</b> , 14,		0
27	Investigation on laser beam figuring of fused silica using microsecond pulsed CO <sub>2</sub> laser radiation. <b>2021</b> , 555, 149609		6
26	Laser ablation of graphite with near infrared microsecond pulses. <b>2021</b> , 127, 1		1
25	Heat accumulation and surface roughness evolution in CO <sub>2</sub> nanosecond laser ablation of quartz glass. <i>Optics and Laser Technology</i> , <b>2021</b> , 144, 107426	4.2	1
24	213 nm laser written waveguides in Ge-doped planar silica without hydrogen loading. <b>2020</b> , 28, 32165-32172		3
23	Interference-based laser-induced micro-plasma ablation of glass. <b>2020</b> , 9, 79-88		2
22	Femtosecond laser $\square$ A powerful tool for micro drilling. <b>1999</b> ,		2
21	Improved surface quality of rotation symmetric structures by excimer laser micromachining. <b>1997</b> ,		1

20	Three dimensional optical storage by use of ultrafast laser. <b>2003,</b>		
19	Surface Micro- and Nano-Structuring of Optically Transparent Materials by Laser-induced Backside Wet Etching. <b>2005,</b> 26, 689-693		
18	A microfluidic bioarray system using laser-machined surface microstructures. <b>2006,</b>		
17	Micromachining of Inorganic Materials using Laser Plasma Soft X-Rays. <i>IEEJ Transactions on Electronics, Information and Systems</i> , <b>2007,</b> 127, 179-184	0.1	1
16	Surface Micro-Structuring of Silica Glass by Laser-induced Backside Wet Etching. <i>The Review of Laser Engineering</i> , <b>2008,</b> 36, 1246-1249	0	
15	Progress in laser-induced backside wet etching. <b>2010,</b>		
14	Hybrid Laser Processing of Transparent Materials. <i>Springer Series in Materials Science</i> , <b>2010,</b> 293-310	0.9	1
13	Tool Making. <i>Lecture Notes in Production Engineering</i> , <b>2013,</b> 201-310	0	1
12	Festkörperlaserabtragung mit Lasern und Dünnschichtabscheidung. <i>Laser in Technik Und Forschung</i> , <b>1993,</b> 226-282		
11	Excimer laser ablation of polymers and glasses for grating fabrication. <b>1996,</b> 537-549		
10	Multiwavelength irradiation effect in fused quartz ablation using vacuum-ultraviolet Raman laser. <b>1996,</b> 347-351		
9	UV generation in silica fibres. <b>2016,</b>		
8	DUV high power lasers processing for glass and CFRP. <b>2017,</b>		2
7	Microdrilling Machinability of Organic Material for Semiconductor Packaging by 248 nm Excimer Laser. <i>Journal of Photopolymer Science and Technology = [Fotopolimer Konwakai Shi]</i> , <b>2020,</b> 33, 499-504	0.7	1
6	Potential of CO-laser processing of quartz for fast prototyping of microfluidic reactors and templates for 3D cell assembly over large scale.. <i>Materials Today Bio</i> , <b>2021,</b> 12, 100163	9.9	2
5	Sub-micrometer pillar formation in fused silica using double-pulse back-surface laser ablation. <i>Optics and Lasers in Engineering</i> , <b>2022,</b> 151, 106935	4.6	1
4	Fast fabrication of diffractive patterns on glass by excimer laser ablation. <i>Optics and Laser Technology</i> , <b>2022,</b> 152, 108148	4.2	1
3	Morphological and ablation characteristics of brass and fused silica after interaction with ArF excimer laser. <i>Optik</i> , <b>2022,</b> 262, 169388	2.5	

- 2 A New Insight into High-Aspect-Ratio Channel Drilling in Translucent Dielectrics with a KrF Laser for Waveguide Applications. **2022**, 15, 8347 ○
- 1 Pulse Burst Generation and Diffraction with Spatial Light Modulators for Dynamic Ultrafast Laser Materials Processing. **2022**, 15, 9059 ○